

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): MEHRDAD NIKOONAHAD ET AL.
Title: SCANNING SYSTEM FOR INSPECTION ANOMALIES ON SURFACES
Application No.: 10/666,120 Filing Date: September 19, 2003
Examiner: Unknown Group Art Unit: 2877
Docket No.: TNCR.001US4 Conf. No.: 8430

Certificate of Mailing Under 37 CFR 1.8

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Signature Eileen Bous

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Dear Sir:

Pursuant to 37 C.F.R. §§ 1.56, 1.97 and 1.98, Applicants call the documents listed on the enclosed Form PTO-1449 to the Examiner's attention in this patent application.

Copies of the documents listed on the accompanying Form PTO-1449 and Form PTO-892 that are not enclosed were previously submitted in Application No. 09/954,287 from which this Application claims an earlier effective filing date.

Citation of these documents shall not be construed as (1) an admission that the documents are prior art with respect to the invention or inventions claimed in this application, (2) a representation that a search has been made (other than as indicated by any cited document), or

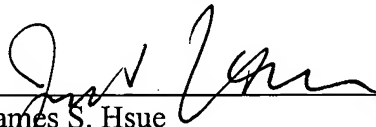
Attorney Docket No.: TNCR.001US4

Application No.: 10/666,120

(3) an admission that the cited information is, or is considered to be, material to patentability as defined in § 1.56(b).

This information disclosure statement is submitted under 37 C.F.R. § 1.97(b) and consequently no fee should be required. The Commissioner is authorized, however, to charge any fee that may be required, or to credit any overpayment, against Deposit Account No. 502664. This form is being submitted in duplicate.

Respectfully submitted,


James S. Hsue
Reg. No. 29,545

2/11/04
Date

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**INFORMATION DISCLOSURE STATEMENT
UNDER 37 CFR § 1.97(b)**

Dear Sir:

Pursuant to 37 C.F.R. § 1.56, § 1.97 and § 1.98, Applicants wish to call the following documents (copies enclosed) to the attention of the Examiner for the above-identified patent application.

A form PTO-1449 listing these documents are enclosed.

Citation of the above documents shall not be construed as:

1. an admission that the documents are necessarily prior art with respect to the instant invention;

2. a representation that a search has been made, a representation that a search has been made, (other than as indicated by any cited document); or

3. an admission that the information cited herein is, or is considered to be, material to patentability as defined in § 1.56(b).

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U.S. Department of Commerce, Patent and Trademark				Atty. Docket No.		Application No.		
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)				TNCR.001US4		10/666,120		
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				Nikoonahad et al.		8430		
				Filing Date		Group		
				9/19/03		2877		
U.S. Patent Documents								
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
U.S. Published Patent Application Documents								
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
Foreign Patent Documents								
							Translation	
		Document	Date	Country	Class	Subclass	Yes	No
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)								
	1	Chang, "Acoustoopic Devices and Applications," <i>IEEE Transactions on Sonics and Ultrasonics</i> , Vol. Su-23, No. 1, January 1976, pp. 1-22.						
	2	Dickson, "Optical Considerations for an Acoustooptic Deflector," <i>Applied Optics</i> , Vol. II, No. 10, Oct. 1972, pp. 2196-2202.						
	3	Young, Jr. et al., "Design Considerations for Acousto-Optic Devices," <i>Proceedings of IEEE</i> , Vol. 69, January 1981, pp. 54-64.						
	4	Uchida et al., "Acoustooptic Deflection Materials and Techniques," <i>Proceedings of the IEEE</i> , Vol. 61, No. 8, August 1973, pp. 1073-1092.						
	5	Randolph et al., "Modulation Transfer Characteristics of an Acoustooptic Deflector," <i>Applied Optics</i> , Vol. 10, No. 6, June 1971, pp. 1383-1385.						
	6	Grossman et al., "High Speed Laser Facsimile Scanner," <i>SPIE, Laser Recording and Information Handling</i> , Vol. 200, 1979, pp. 8-15.						
	7	Merry, "High Resolution Acoustooptic Deflector Demonstrated in a Laser Scanner," pp. 32-34.						
	8	"All About Bragg Angle Errors in Acousto-Optic Modulators and Deflectors," <i>ISOMET</i> , May 1993, pp. 1-23.						
	9	Bademian, "Acousto-Optical Deflectors," <i>ISOMET</i> , May 1993, pp. 1-32.						

	10	Alcousis-Optic Deflectors," <i>ISOMET</i> , pp. 1-9
Examiner	FEB 13 2004	Date Considered
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.		

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Atty Docket No.

Serial No.

TNCR.001US3

09/954,287

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT BY APPLICANT

Applicant(s)

(Use several sheets if necessary)

MEHRDAD NIKOONAHAD ET AL.

Filing Date

Group

September 11, 2001

2877

U.S. Patent Documents

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	A1	4,794,264	12/27/98	Quackenbos et al.	250	563	
	A2	5,888,710	03/30/99	Adachi et al.	430	523	
	A3	5,903,342	05/11/99	Yatsugake et al.	356	237.4	
	A4	6,081,325	06/27/00	Leslie et al.	356	237.2	
	A5	6,292,259	09/18/01	Fossey et al.	356	237.2	
	A6						
	A7						
	A8						
	A9						
	A10						
	A11						

Foreign Patent Documents

							Translation	
		Document	Date	Country	Class	Subclass	Yes	No
	B1	63-284455	11/21/88	Japan			Yes	
	B2	H5-332946	12/17/93	Japan			Yes	
	B3							
	B4							
	B5							

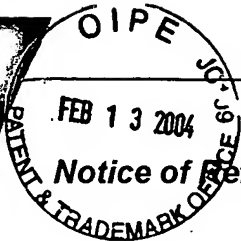
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

C1	"Discrete Sources Method For The Silicon Wafers Defect Discrimination," Yuri Eremin and N. Orlov, <i>J. 12th Annual Review of Progress in Applied Computational Electromagnetics</i> , March 18-22, 1996, pp. 758-763
C2	"Determination of COP Distribution After SC1 Cleaning By A Laser Particle Counter," T. Fujise, et al., <i>Optical Characterization Techniques For High-Performance Microelectronic Device Manufacturing III</i> , SPIE Proc. Vol. 2877, Oct. 16, 19978, pp. 16-25
C3	

Examiner

Date Considered

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Notice of References Cited

Application/Control No.

09/954,287

Applicant(s)/Patent Under
Reexamination
NIKOONAHAD ET AL.

Examiner

Richard A Rosenberger

Art Unit

2877

Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-5,125,741	06-1992	Okada et al.	356/237.2
	B	US-6,118,525	09-2000	Fossey et al.	356/237.2
	C	US-			
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	
	V	
	W	
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.

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2877

U.S. Patent Documents

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	A1	3,851,951	12/1974	Eveleth		
	A2	4,277,178	7/1981	Cushing et al.		
	A3	4,306,808	12/1981	Vander Neut		
	A4	4,376,583	3/1983	Alford et al.		
	A5	4,378,159	3/1983	Galbraith		
	A6	4,391,238 524	9/1983	Steigmeier et al.		
	A7	4,405,238	9/1983	Grobman et al.		
	A8	4,441,124	4/1984	Heebner et al.		
	A9	4,526,468	7/1985	Steigmeier et al.		
	A10	4,556,290	12/1985	Roulot		
	A11	4,589,773	5/1996	Ido et al.		

Foreign Patent Documents

							Translation	
	Document	Date	Country	Class	Subclass		Yes	No
	B1	065051A2	12/1981	Europe				
	B2	2-78936	3/1990	Japan			Yes	
	B3	2-87047	3/1990	Japan			Yes	
	B4	3-225939	10/1991	Japan			Yes	
	B5	6-34559	2/1994	Japan			Yes	

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

C1	"Dynamic performance of a scanning X-Y stage for automated electron-beam inspection," D.J. Clark et al., <i>J. Vac. Sci. Technol. B</i> , Vol. 10, No. 6, Nov/Dec 1992, pp. 2638-2642
C2	"Inspection of Patterned Wafers: 0.35 μ m Design Rules and Beyond," J.R. Dralla et al., presented at Semicon Kansai Japan, 1994, pp. 1-8
C3	"Acoustooptic Scanners and Modulators," publication of Westinghouse Electric Corporation, Gottlieb, pp. 615-685

Examiner

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U.S. Patent Documents

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	A12	4,598,997	7/1986	Steigmeier et al.		
	A13	4,601,576	7/1986	Galbraith		
	A14	4,614,427	9/1986	Koizumi et al.		
	A15	4,650,983	3/1987	Suwa		
	A16	4,728,190	3/1988	Knollenberg		
	A17	4,740,708	4/1988	Batchelder		
	A18	4,748,333	5/1988	Mitzutani et al.		
	A19	4,752,898	6/1988	Koenig		
	A20	4,766,324	8/1988	Saadat et al.		
	A21	4,772,126	9/1988	Allemand et al.		
	A22	4,786,815	11/1988	Walker et al.		

Foreign Patent Documents

	Document	Date	Country	Class	Subclass	Translation	
						Yes	No
B6	62-153737	7/1987	Japan			Yes	
B7	62-274633	11/1987	Japan			Yes	
B8	63-73635	4/1988	Japan			Yes	
B9	62-128135	6/1987	Japan			Yes	
B10	6-174655	6/1994	Japan			Abstract	

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

C4	"A stand-alone scanning force and friction microscope," M. Hipp et al., <i>Ultramicroscopy</i> , 42-44 (1992), pp. 1498-1503
C5	"Dual Sensor Technology for High Speed Detection of 0.1 Micron Defects," Alumont et al., <i>SPIE</i> , Vol. 1926 "Integrated Circuit Metrology, Inspection and Process Control VII," 1993, pp. 1-12
C6	"New Laser Scanning Techniques for Wafer Inspection," M. Nikoonahad et al. <i>SPIE</i> , Vol. 2638, February 1995, pp. 285-301

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U.S. Patent Documents

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	A23	4,800,268	1/1989	Miyoshi et al.		
	A24	4,844,617	7/1989	Kelderman et al.		
	A25	4,864,123	9/1989	Mizutani et al.		
	A26	4,864,147	9/1989	Ikari et al.		
	A27	4,889,998	12/1989	Hayano et al.		
	A28	4,895,446	1/1990	Maldari et al.		
	A29	4,898,471	2/1990	Stonestrom et al.		
	A30	4,899,055	2/1990	Adams		
	A31	4,912,487	3/1990	Porter et al.		
	A32	4,936,676	6/1990	Stauffer		
	A33	4,966,457	10/1990	Hayano et al.		
	A34	4,998,019	3/1991	Stokowski et al.		
	A35	5,004,929	4/1991	Kakinoki et al.		
	A36	5,027,132	6/1991	Manns et al.		
	A37	5,076,692	12/1991	Neukermans et al.		
	A38	5,083,035	1/1992	Pecen et al.		

Foreign Patent Documents

Document	Date	Country	Class	Subclass	Translation
					Yes No

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

C7	"Scatterometers Improve Laser Mirrors," G. Valliant, TMA Technologies, Inc., <i>Photonics Spectra</i> , Vol. 25, Issue 8, August 1991, p. 100
C8	"Windowing effects on light scattering by sinusoidal surfaces," E. Marx et al., <i>SPIE</i> , Vol. 1995 Optical Scattering, 1993, pp. 2-14
C9	"A Light Scattering and Distribution Model for Scintillation Cameras," S. Rioux et al., <i>SPIE</i> , Vol. 1995 Optical Scattering, 1993, pp. 15-25

Examiner

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U.S. Patent Documents

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	A39	5,092,557	3/1992	Sawatzki			
	A40	5,122,898	6/1992	Picault			
	A41	5,162,642	11/1992	Akamatsu et al.			
	A42	5,166,516	11/1992	Kajimura			
	A43	5,168,386	12/1992	Galbraith			
	A44	5,241,366	8/1993	Bevis et al.			
	A45	5,133,635	7/1992	Malin et al.			
	A46	5,264,912	11/1993	Vaught et al.			
	A47	5,272,517	12/1993	Tokura			
	A48	5,274,434	12/1993	Morioka et al.			
	A49	5,317,380	5/1994	Allemand			
	A50	5,363,187	11/1994	Hagiwara et al.			
	A51	5,436,464	7/1995	Hayano et al.			
	A52	5,461,474	10/1995	Yoshii et al.			
	A53	5,576,831	11/1996	Nikoonahad et al.			
	A54	5,659,390	8/1997	Danko			

Foreign Patent Documents

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					Yes	No

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

C10	"Diffuse Reflection From Smooth Dielectric Surfaces," L. Wolff, <i>SPIE</i> Vol. 1995 Optical Scattering, 1993, pp. 26-44
C11	"Plane-wave expansions methods applied to the calculation of the optical scattering by one-dimensional randomly rough dielectric surfaces," S. Mainguy, <i>SPIE</i> Vol. 1995 Optical Scattering, 1993, pp. 45-56
C12	"The Wavelength Dependence of Scatter From 0-50 Grade Beryllium Mirrors," C.M. Egert, <i>SPIE</i> Vol. 1995 Optical Scattering, 1993, pp. 57-65

Examiner

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U.S. Patent Documents

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	A55	5,742,422	4/1998	Drake		
	A56	5,712,701	1/1998	Clementi et al.		
	A57	5,742,422	4/1998	Drake		
	A58	5,805,278	9/1998	Danko		

Foreign Patent Documents

Document	Date	Country	Class	Subclass	Translation
					Yes No

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

C13	"Extracting the Scattering Coefficient of Sea Water From the Return Time Signal of Ocean Lidar," J. Zhang, <i>SPIE</i> Vol. 1995 Optical Scattering, 1993, pp. 74-78
C14	"Preparing Samples for Scattering Measurements - A Cleaning Study: Part 2, J. Brown, <i>SPIE</i> Vol. 1995 Optical Scattering, 1993, pp. 80-91
C15	"Design review of an instrument to map low level hydrocarbon contamination," B. Swimley et al., <i>SPIE</i> Vol. 1995 Optical Scattering, 1993, pp.92-120
C16	"Design review of a high accuracy UV to near IR scatterometer," T. Schiff et al., <i>SPIE</i> Vol. 1995 Optical Scattering, 1993, pp. 121-130
C17	"Design review of a unique laser monostatic bidirectional reflectometer," Z. Gu et al., <i>SPIE</i> Vol. 1995 Optical Scattering, 1993, pp. 131-142
C18	"Sources of error in spectroscopic, low level integrated light scattering measurements," D. Rönnow, <i>SPIE</i> Vol. 1995 Optical Scattering, 1993, pp. 143-151
C19	"A New Generation High Speed, High Resolution, Hemispherical Scatterometer," R. Castonguay, <i>SPIE</i> Vol. 1995 Optical Scattering, 1993, pp. 152-165
C20	"Real-time detection of surface damage by direct assessment of the BRDF," H. Rothe et al., <i>SPIE</i> Vol. 1995 Optical Scattering, 1993, pp. 168-180
C21	"Microtopography investigations of optical surfaces and thin films by light scattering, optical profilometry, and atomic force microscopy," A. Duparré et al., <i>SPIE</i> Vol. 1995 Optical Scattering, 1993, pp. 181-192

Examiner

Date Considered

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		Document	Date	Country	Class	Subclass	Translation		
							Yes	No	
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)									
	C22	"Characterization of Curved Plastic Surfaces," Q. Y. Xie et al., <i>SPIE</i> Vol. 1995 Optical Scattering, 1993, pp. 193-201							
	C23	"Reflection, scattering, and polarization from a very rough black surface," S.F. Nee et al., <i>SPIE</i> Vol. 1995 Optical Scattering, 1993, pp. 202-212							
	C24	"Very high angular selectivity system for measuring backscatter from rough surfaces," Y. Takakura et al., <i>SPIE</i> Vol. 1995 Optical Scattering, 1993, pp. 213-222							
	C25	"Scattering Properties of very rough surfaces: Application to brightness measurement of common objects," P. Sandoz et al., <i>SPIE</i> Vol. 1995 Optical Scattering, 1993, pp. 223-234							
	C26	"A Step-Height Standard for Surface Profiler Calibration," P. Takacs et al., <i>SPIE</i> Vol. 1995 Optical Scattering, 1993, pp. 235-244							
	C27	"High temperature optical scatter characteristics of CVD diamond and natural type IIa diamond," M.B. McIntosh et al., <i>SPIE</i> Vol. 1995 Optical Scattering, 1993, pp. 246-255							
	C28	"Wavelength scaling investigation of several materials," J. C. Stover et al., <i>SPIE</i> Vol. 1995 Optical Scattering, 1993, pp. 256-266							
	C29	"Mueller Matrix measurements of several optical components," J.C. Stover et al., <i>SPIE</i> Vol. 1995 Optical Scattering, 1993, pp. 267-272							
	C30	"Bulk scatter measurements in fused silica at two wavelengths: A comparison with Rayleigh scatter theory," J. P. Black et al., <i>SPIE</i> Vol. 1995 Optical Scattering, 1993, pp. 273-284							
	C31	"BRDF Round Robin Test of ASTM E1392," T.A. Leonard et al., <i>SPIE</i> Vol. 1995 Optical Scattering, 1993, pp. 285-293							
Examiner			Date Considered						
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U.S. Patent Documents

*Examiner
InitialDocument
Number

Date

Name

Class

Subclass

Filing Date
If Appropriate

Foreign Patent Documents

Document

Date

Country

Class

Subclass

Translation

Yes

No

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

C32

"Experimental scattering investigations and radiative transfer calculations of large arbitrarily shaped absorbing particles," C. Sasse, *SPIE* Vol. 1995 Optical Scattering, 1993, pp. 294-299 ✓

C33

"Meeting the Challenges of Unpatterned Wafer Inspection for 130nm Device Geometries," H. Altendorfer et al., *Silicon Wafer Symposium, SEMI* 1998, pp. K-1 - K-8

C34

"COPs/Particles Discrimination with a Surface Scanning Inspection System," M. Akbulut et al., *Semiconductor International*, April 1999, pp. 1-6

C35

"Comparison of models and measurements of scatter from surface bound particles," C.A. Scheer et al., *SPIE*, Vol. 3275, pp. 102-111

C36

"Comparison of Measured and Modeled Scatter from Defects and Particles on Silicon Wafers," J.C. Stover et al., *Electromagnetic and Light Scattering: Theory and Applications*, Workshop 1997, pp. 109-118

C37

"Experimental Verification of Discrete Sources Method in Problem of Light Scattering from Particle Upon Wafer Surface," pages 1-11 with 6 sheets of figures

C38

"Response of a Wafer Surface Scanner to Non-Ideal, Real World Particles," S. Chae et al., *Particle Technology Laboratory Publication No. 820*, January 1992, 10 pages

C39

"Using calibration curve modeling for scanning surface inspection systems," R.S. Howland et al., *Analytical Technologies*, July/August 1995 MICRO, pp. 61-71

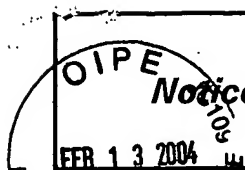
C40

"Measurement of hemispherical directional reflectance in the infrared," J.T. Neu, *SPIE, Optical Scanning*, Vol. 1995, 1993, pp. 101-120

Examiner

Date Considered

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.



Notice of References Cited

Applicant/Patent NIKOONAHAD et al	Application/Control No. 09/760,558
Examiner Richard Rosenberger	Art Unit 2877

Page 1 of 1

U.S. PATENT DOCUMENTS

	Document Number <small>Country Code-Number-Kind Code</small>	Date <small>MM-YYYY¹</small>	Name	Classification ²	
A	4,740,708	4/1988	BATCHELDER	356	237.3
B	4,898,471	2/1990	STONESTROM et al	356	237.4
C	5,883,710	3/1999	NIKOONAHAD et al	356	237.2
D	6,215,551	4/2001	NIKOONAHAD et al	356	237.2
E					
F					
G					
H					
I					
J					
K					
L					
M					

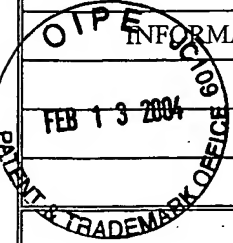
FOREIGN PATENT DOCUMENTS

	Document Number <small>Country Code-Number-Kind Code</small>	Date <small>MM-YYYY¹</small>	Country	Name	Classification ²	
N						
O						
P						
Q						
R						
S						
T						

NON-PATENT DOCUMENTS

	Include, as applicable: Author, Title, Date, Publisher, Edition or Volume, Pertinent Pages
U	
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X	

* A copy of this reference is not being furnished with this Office action. See MPEP § 707.05(a). ¹ Dates in MM-YYYY format are publication dates. ² Classifications may be U.S. or foreign.

U.S. Department of Commerce, Patent and Trademark Office				Atty Docket No.		Serial No.		
				M-10575-2C US		09/760,558		
				Applicant(s)				
(Use several sheets if necessary)				MEHRDAD NIKOONAHAD ET AL.				
				Filing Date		Group		
				January 16, 2001		2877		
U.S. Patent Documents								
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
	AA	Re. 33,991	7/14/92	Shiba et al.	356	237		
	AB	5,189,481	2/23/93	Jann et al.	356	73		
	AC							
	AD							
	AE							
	AF							
	AG							
	AH							
	AI							
	AJ							
	AK							
Foreign Patent Documents								
							Translation	
		Document	Date	Country	Class	Subclass	Yes	No
	AL							
	AM							
	AN							
	AO							
	AP							
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)								
	AQ	ISOMET Corporation Specification for LS-55 V Acousto Optic Deflector/AOT, 4 pages						
	AR							
	AS							
Examiner			Date Considered					
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